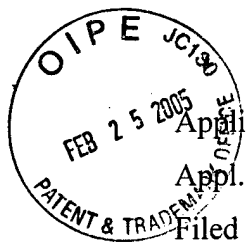


IRL

ASMJP.135AUS

PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE



Applicant : Kamal Kisho Goundar  
Appl. No. : 10/616,163  
Filed : July 9, 2003  
For : METHOD OF FORMING  
SILICON CARBIDE FILMS  
Examiner : Monica D Harrison  
Group Art Unit : 2829

CERTIFICATE OF MAILING

I hereby certify that this correspondence and all marked attachments are being deposited with the United States Postal Service as first-class mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450, on

February 22, 2005

(Date)

Katsuhiro Arai, Reg. No. 43,315

AMENDMENT

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

In response to the Office Action mailed September 22, 2004, please reconsider the present application in light of the following amendments and comments.

**Amendments to the Claims** are reflected in the listing of claims which begins on page 2 of this paper.

**Remarks/Arguments** begin on page 5 of this paper.

02/28/2005 CCHAU1 00000018 10616163

02 FC:1252

450.00 0P